# Monthly LabAdviser update: 6/6 2016

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| Updated Subject | Contributor | Link to the updated pages |
| **Solar cell process flow**  The solar cell process flow has been updated. | **Karen Birkedal @danchip** | [Solar\_cell\_process\_flow](http://labadviser.danchip.dtu.dk/index.php/LabAdviser/Introduction_to_LabAdviser_and_Processing/Solar_cell_process_flow) |
| **New equipment in/old equipment out**  The page showing which pieces of equipment are entering/leaving Danchip has been updated. | **Anders M. Jørgensen and Berit Herstrøm @danchip** | [New\_equipment\_in\_the\_pipeline\_and\_Old\_equipment\_for\_decommissioning](http://labadviser.danchip.dtu.dk/index.php/LabAdviser/New_equipment_in_the_pipeline_and_Old_equipment_for_decommissioning) |
| **DUV stepper**   * Added a section on process instructions * Added advice on Reticle design * Added page on optimization and simulation | **Matthias Keil @danchip** | [Process\_Instructions](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Lithography/DUVStepperLithography/Process_Instructions)  [Reticle\_Design](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Lithography/DUVStepperLithography/Reticle_Design)  [Optimization\_and\_Simulation](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Lithography/DUVStepperLithography/Optimization_and_Simulation) |
| **ALD**   * Al2O3 deposition page has been updated with XPS investigation, deposition on HAR structures and with ozone recipe * TiO2 deposition page has been updated with a lot of things (morphology studies, XPS results, deposition on trenches). * ALD multilayers: new page | **Evgeniy Shkondin @danchip** | [Al2O3\_deposition\_using\_ALD](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/ALD_Picosun_R200/Al2O3_deposition_using_ALD)  [TiO2\_deposition\_using\_ALD](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/ALD_Picosun_R200/TiO2_deposition_using_ALD)  [ALD\_multilayers](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/ALD_Picosun_R200/ALD_multilayers) |
| **DRIE Pegasus**   * Updated several sub-pages * New page about etching with DUV mask * New page on isotropic etch | **Jonas Michael-Lindhard @danchip** | [DRIE-Pegasus](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Etch/DRIE-Pegasus)  [DRIE-Pegasus/DUVetch](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Etch/DRIE-Pegasus/DUVetch)  [DRIE-Pegasus/Isotropic](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Etch/DRIE-Pegasus/Isotropic) |
| **AFM**  Some training videos have been produced. A link to the videos can be found on the AFM equipment page | **Berit Herstrøm @danchip.dtu.dk** | [AFM:\_Atomic\_Force\_Microscopy](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Characterization/AFM:_Atomic_Force_Microscopy) |
| **E-beam resist**  Updated process flow in ‘CSAR with Al’ | **Tine Greibe @danchip** | [EBeamLithography#E-beam\_resists\_and\_Process\_Flows](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Lithography/EBeamLithography#E-beam_resists_and_Process_Flows) |

# Equipment Manuals updated in LabManager:

As an approved user on a piece of equipment you have to make sure you have read and understood the latest version of the manual before using the equipment.

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|  | **Manual for Polymer Injection Molding** |

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